

Notice of References Cited	Application/Control No. 10/821,755		Applicant(s)/Patent Under Reexamination BELFIELD, KEVIN D.	
	Examiner Martin J. Angebranndt		Art Unit 1756	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2003/0073031	04-2003	Rentzepis et al.	430/270.15
*	B	US-7,001,708	02-2006	Belfield, Kevin D.	430/280.1
*	C	US-6,212,148	04-2001	Hesselink et al.	369/103
*	D	US-6,071,671	06-2000	Glushko et al.	430/270.15
*	E	US-2003/0027063	02-2003	Fourkas et al.	430/19
*	F	US-6,608,228	08-2003	Cumpston et al.	564/308
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	01/96959	12-2001	WIPO	Fleming et al.	**
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Belfield et al. "Three dimensional two photon imaging in polymeric materials" Proc. SPIE vol. 4459 pp. 281-289 (01/2002)
	V	Tanaka et al. "Rapid sub-diffraction limit laser micro/nano processing in a threshold material system", Appl. Phys. Lett., Vol. 80(2) pp. 312-314 (01/2002)
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.